

# PATENT ABSTRACTS OF JAPAN

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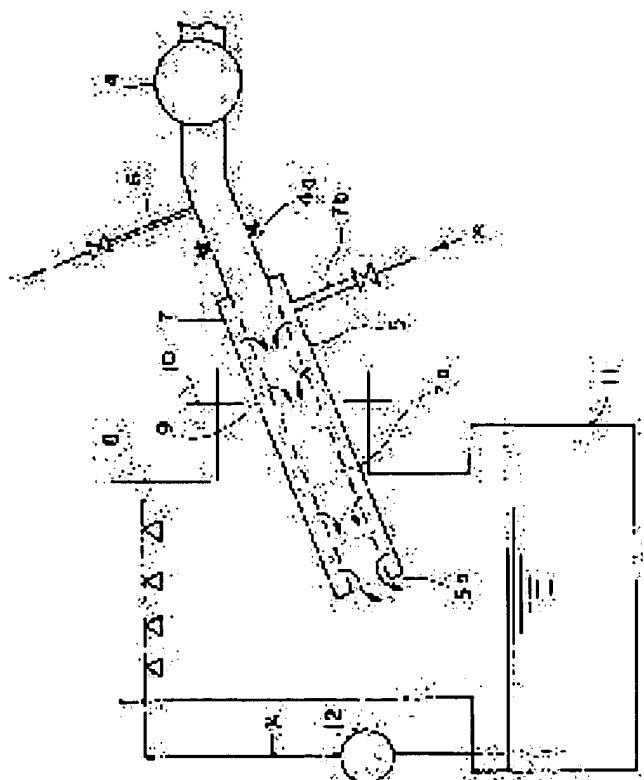
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## (54) DISCHARGE GAS TREATING DEVICE

### (57)Abstract:

**PURPOSE:** To prevent solid fine particles generated by combustion from sticking to pipe wall, etc., by providing a connecting liquid-streaming part of washing liquid to the inner wall of a gas introducing pipe introducing a discharge gas containing a spontaneous ignition toxic gas to a combustion chamber.

**CONSTITUTION:** A double pipe structure 7 is provided with numerous spouting openings to an area of a certain length (l) from the open end 5a of the discharge gas introducing pipe 5 which introduces a gas containing a spontaneous ignition toxic gas, such as silane gas, discharged from a semiconductor manufacturing process to a shower washing chamber 8 used also as a combustion chamber. SiH<sub>4</sub>, etc., are spontaneously ignited by bringing into contact with air, and fine particles of



SiO<sub>2</sub>, etc., produced by combustion are always washed out by a washing liquid, such as an alkaline aqueous solution, along all the inner peripheral surface of the introducing pipe 5, and, as a result, the clogging of the open end 5a is surely prevented.